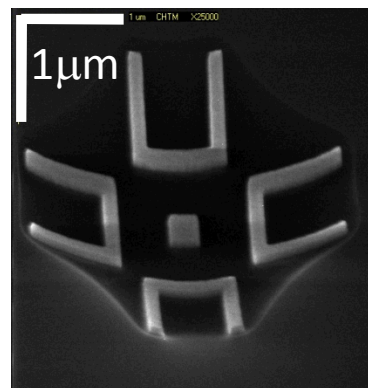
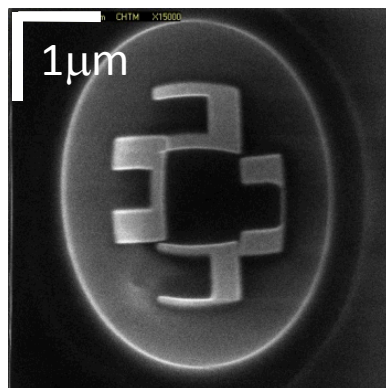




Metamaterials Science & Technology

SAND2010-0217C

3-D Metamaterial Fabrication Using Membrane Projection Lithography



D. Bruce Burckel, P. Davids, I. Brener, G. A. Ten Eyck,
A. R. Ellis, J. R. Wendt, and M. B. Sinclair

dbburck@sandia.gov

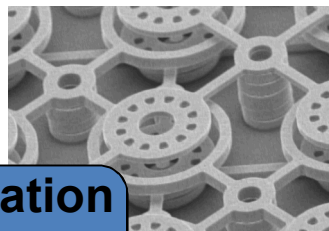
Sandia is a multiprogram laboratory operated by Sandia Corporation, a Lockheed Martin Company,
for the United States Department of Energy's National Nuclear Security Administration
under contract DE-AC04-94AL85000.





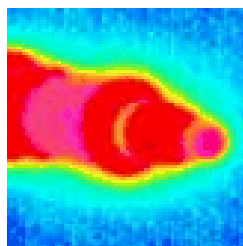
Metamaterials Science & Technology

Sandia's MST Program at a Glance

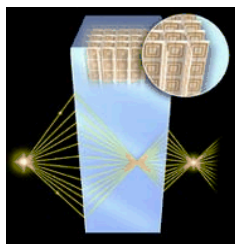


**fabrication
&
testing**

- DUVL, EBL, PnP, NIL
- spectroscopic phase meas.



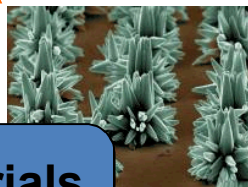
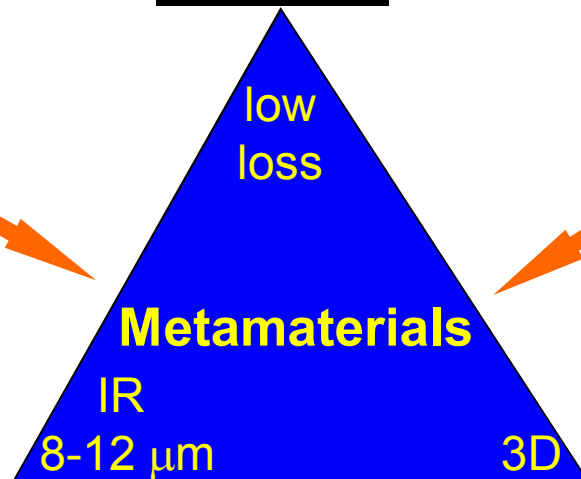
- thermal IR
- limits to shorter- λ



- <0.1 db/Wave
- perfectly absorbing structures

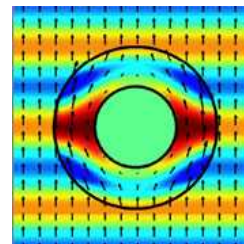
**theory
&
modeling**

- loss fundamentals
- MPP HPC design environment
- full anisotropic optimization



**materials
science**

- dielectrics/composites/alloys
- low-n polymer 3D matrix materials



- volumetric energy flow, large area
- multiple directions
- multiple polarizations

**university
Partners**



Concept of Metamaterials

Metamaterials Science & Technology

In a conventional material, the permittivity ϵ , & permeability μ are derived from the constituent atoms

In a metamaterial, ϵ_{eff} , μ_{eff} are derived from "meta-units" (bigger than atoms, $\ll \lambda$)

Absolute local control of ϵ and μ

after Pendry, JB, 'Negative refraction', Contemporary Physics, 45:3, 1994, 2002

refractive index: $n = \sqrt{\mu\epsilon}$

wave impedance: $\eta = \sqrt{\frac{\mu}{\epsilon}}$

Sandia National Laboratories



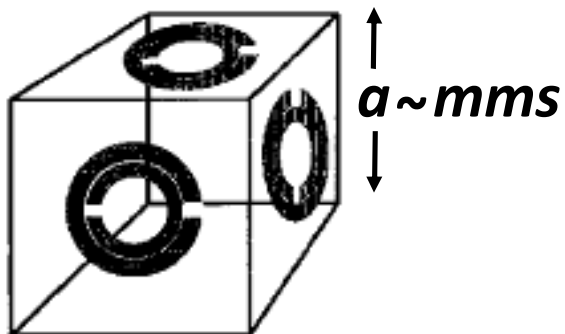
Metamaterials Science & Technology

RF/Microwave Metamaterials

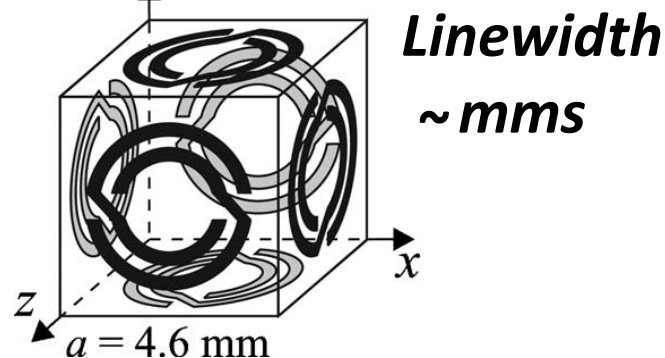
$$1 < \epsilon_r < 300$$

$$1 < \mu_r < 30$$

Notional
Design



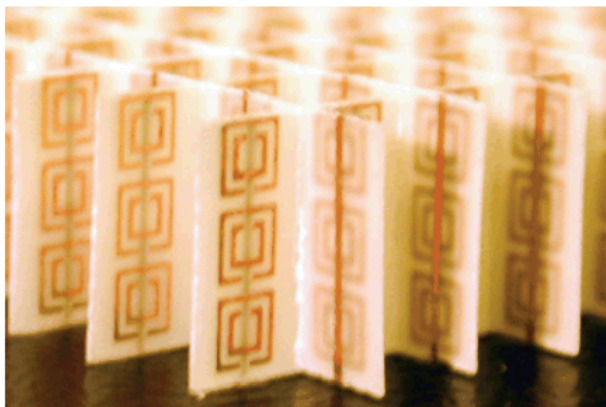
Pendry, IEEE Trans on Microwave Theory and Techniques
47, #11, 2075 (1999)



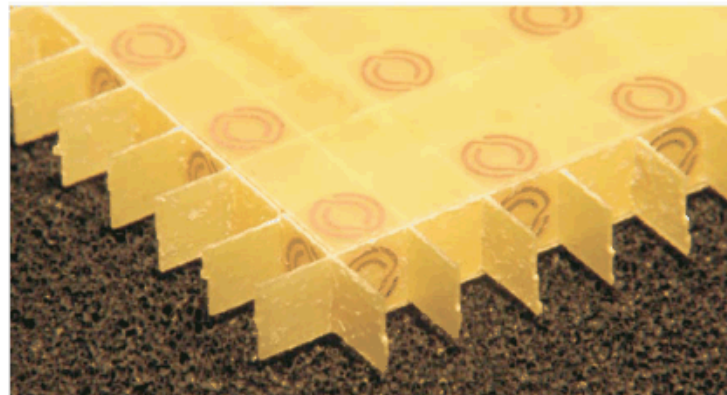
Baena, APL 91, 191105, (2007)



Experiment



Schultz, Science 292, 77, (2001)



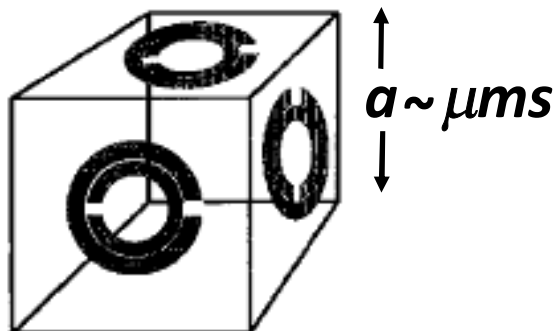
Baena, APL 91, 191105, (2007)



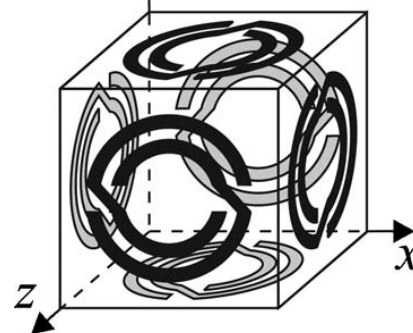
Metamaterials Science & Technology

RF/ μ Wave Designs \rightarrow IR/Optical

$$1 < \epsilon_r < 40$$



$$\mu_r = 1$$



Linewidth
 $\sim 100\text{nm}$

Material Challenges

- Maximum ϵ_r and μ_r are OOM smaller than for RF frequencies
- Metals become lossy at IR and optical frequencies

Fabrication Challenges

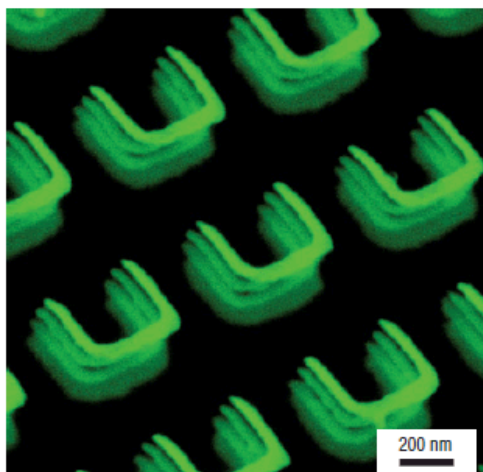
- Linewidths require advanced lithography
- Most advanced lithography techniques have short depth of focus – can only form planar patterns
- Post processing assembly not possible at these size scales – Full resonator must be fabricated in place
- Out-of-plane features are limited in aspect ratio by typical etch/deposition methods



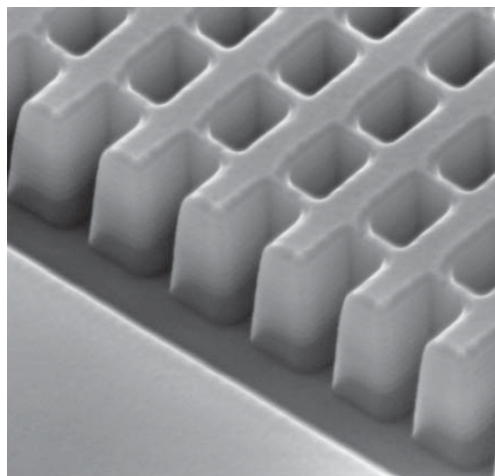
Metamaterials Science & Technology

IR and Optical Metamaterials

Stacked Planar

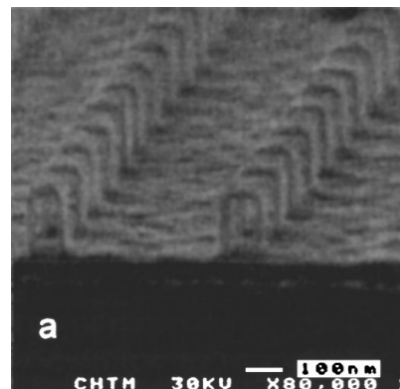


Giessen- Nature Mat **7**, 31, (2008)

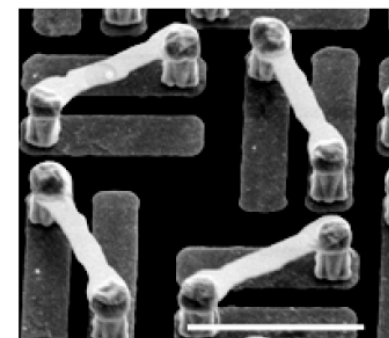


Zhang, Nature **455**, 376 (2008)

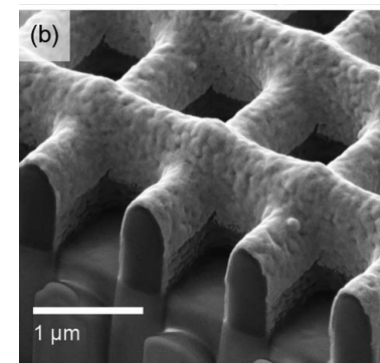
Out-of-Plane Current



Brueck - JOSA B **23**, #3, 434, (2004)



Zhang, PRL **102**, 023901, (2009)

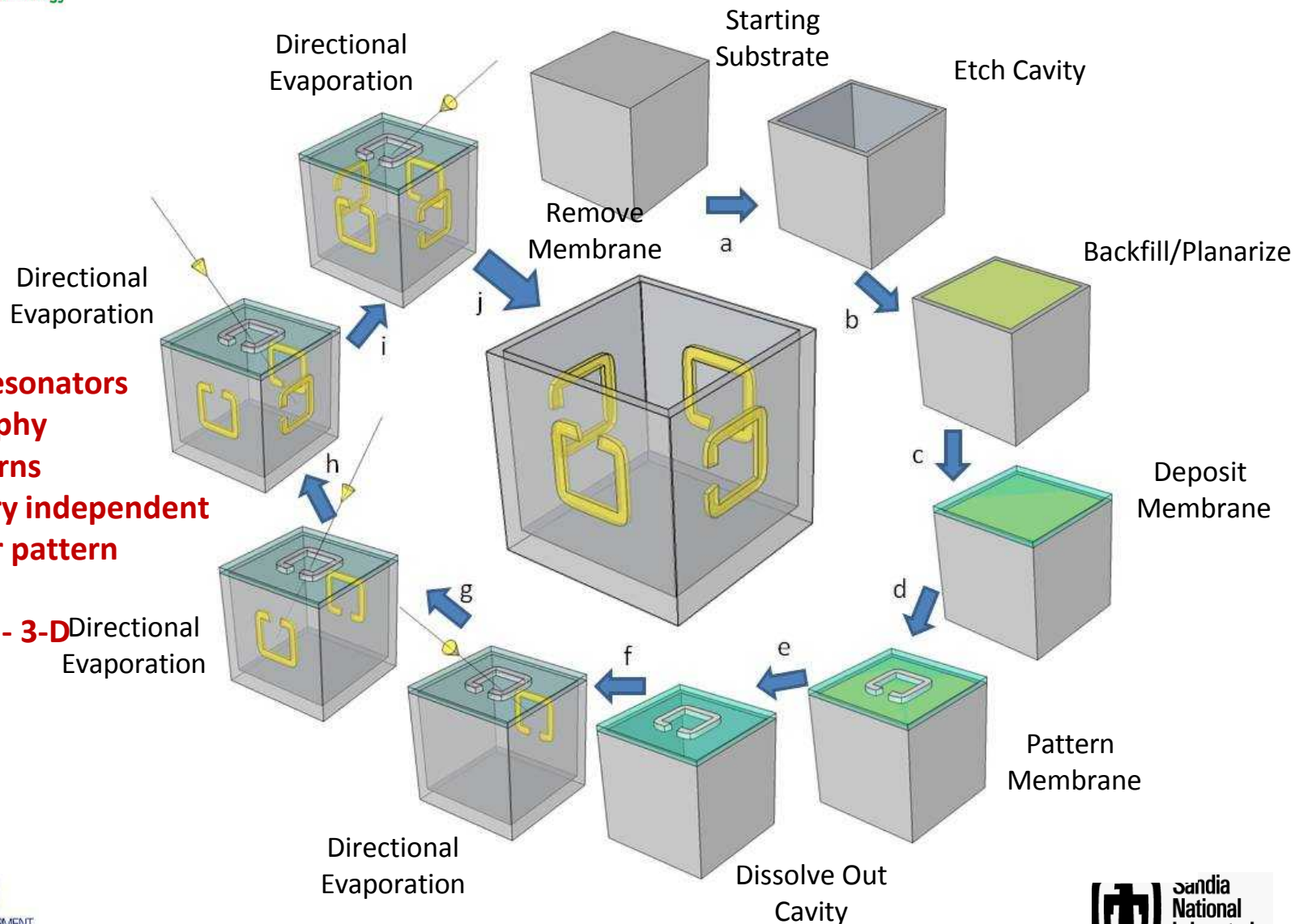


Wegener, Optics Lett **34**, 16, (2009)



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Membrane Projection Lithography

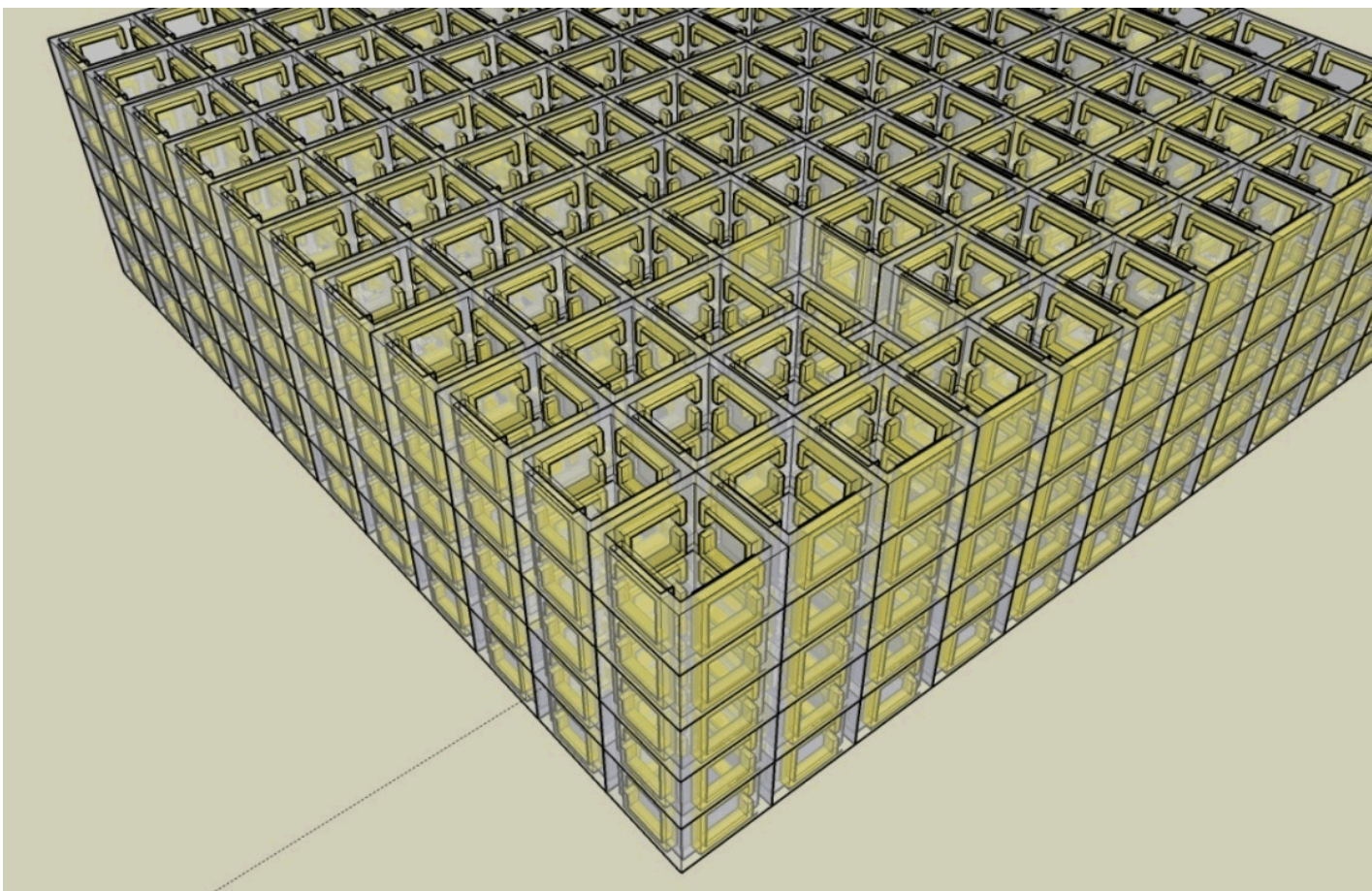


- Out-of-plane resonators
- Planar lithography
- Arbitrary patterns
- Cavity geometry independent from resonator pattern
- Scalable
- Layer-by-layer - 3-D



Metamaterials Science & Technology

Layer-by-layer Route To 3D Material

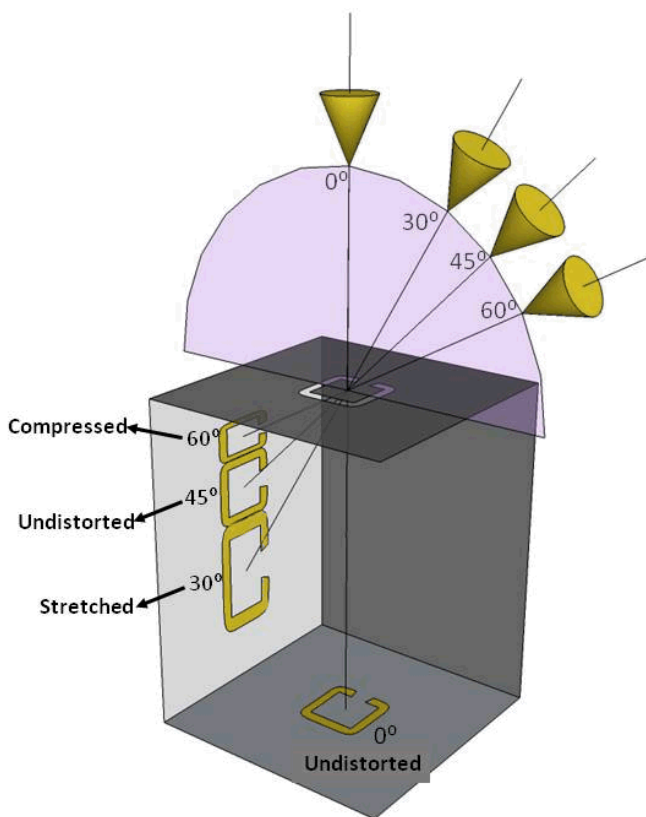




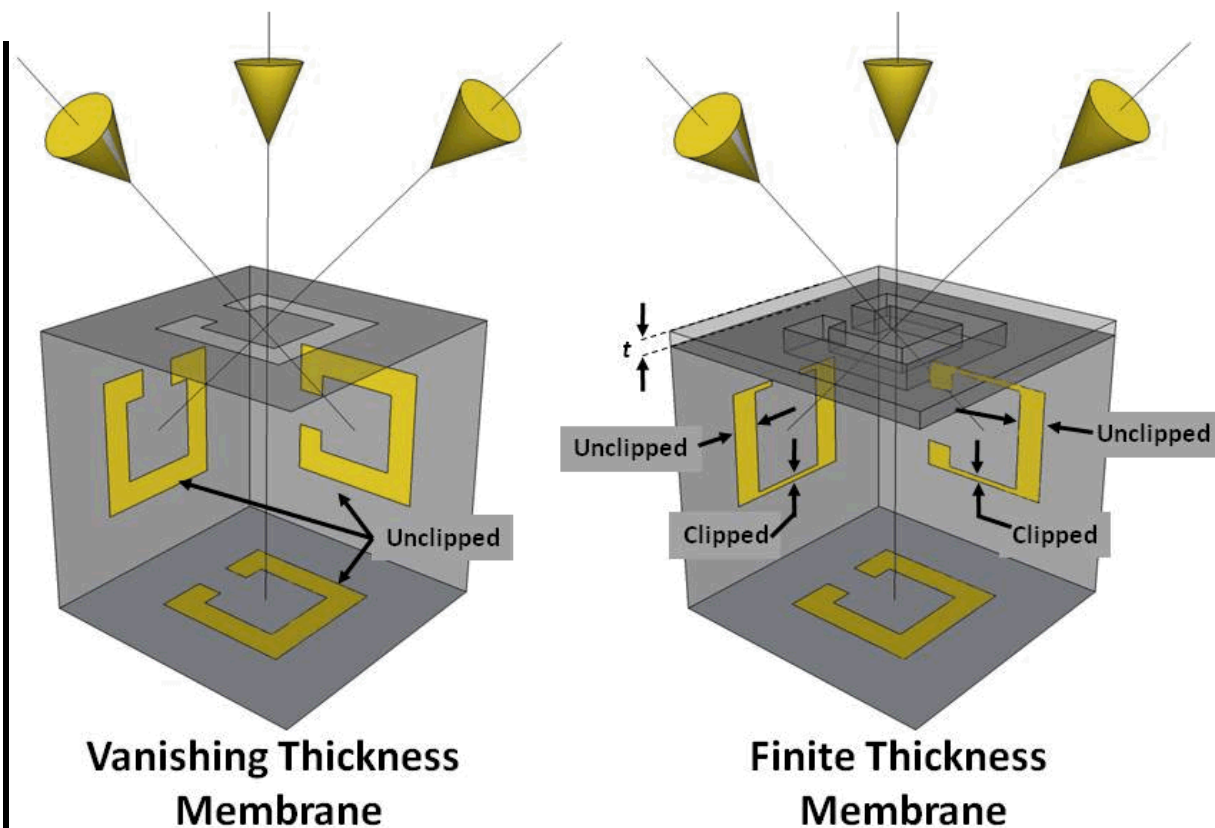
Metamaterials Science & Technology

Real Membranes result in Linewidth Clipping

Projection at 45°
Preserves Pattern Shape



Real Membranes result in Linewidth Clipping



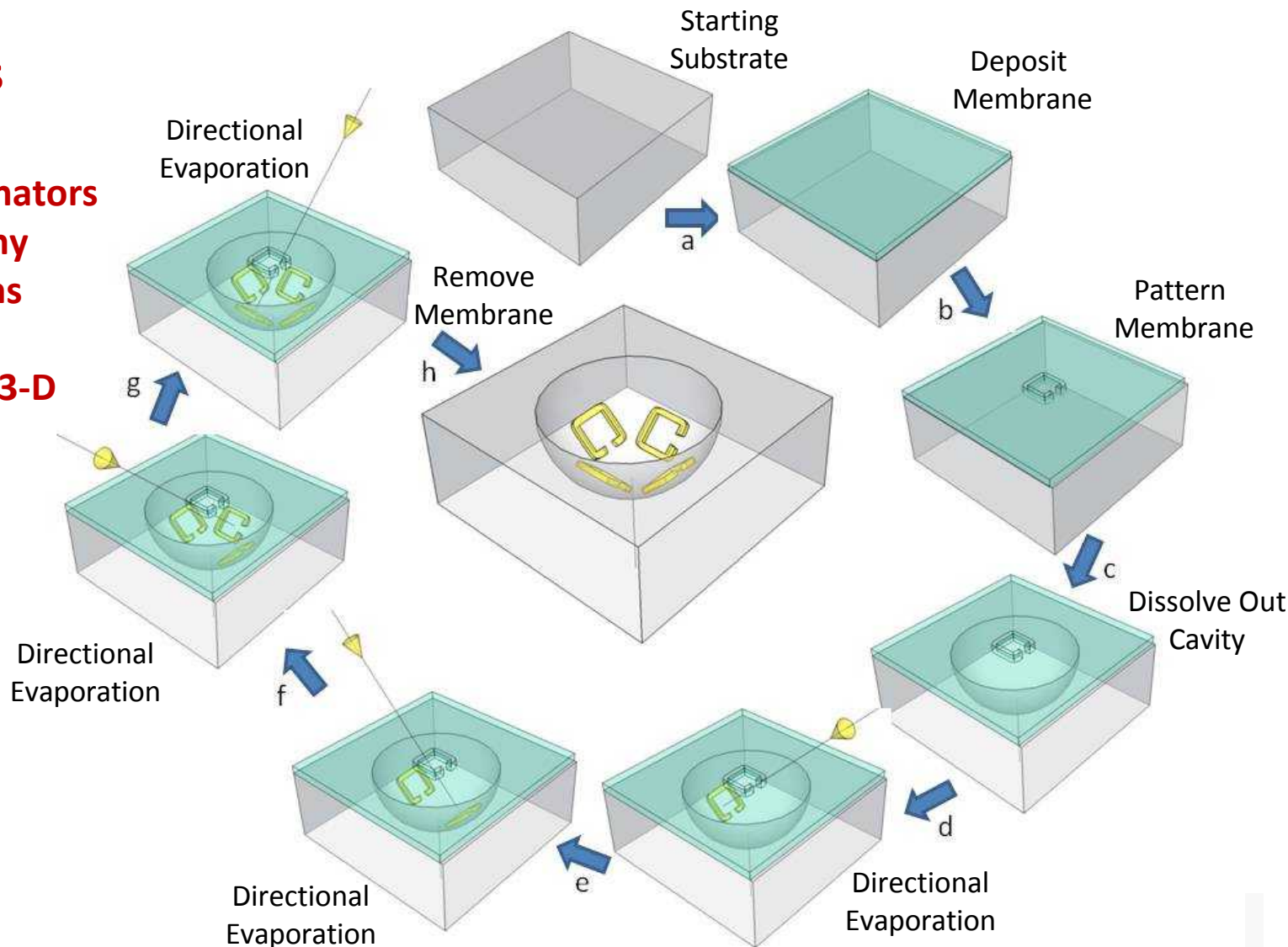


Metamaterials Science & Technology

Self-Aligned MPL

Advantages

- Self-Aligned
- Non-planar resonators
- Planar lithography
- Arbitrary patterns
- Scalable
- Layer-by-layer - 3-D

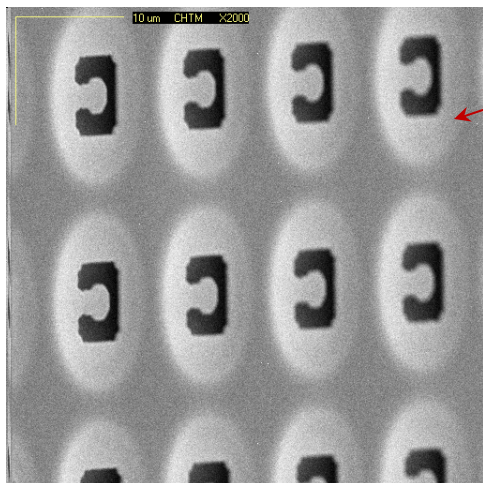




SAMPL – Patterned Membranes

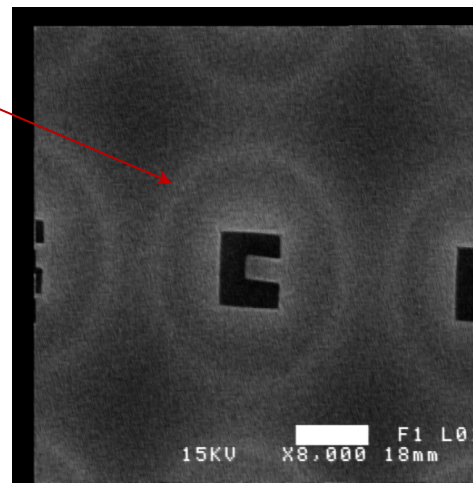
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Contact Lithography

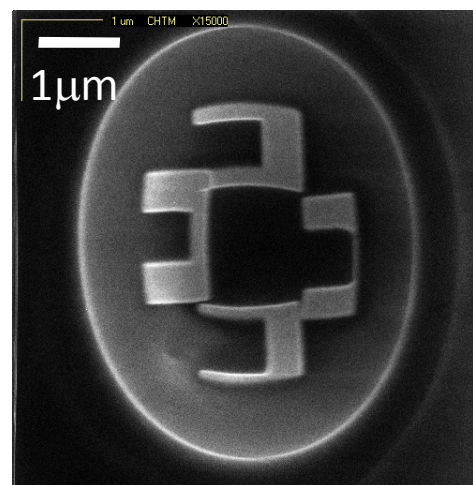
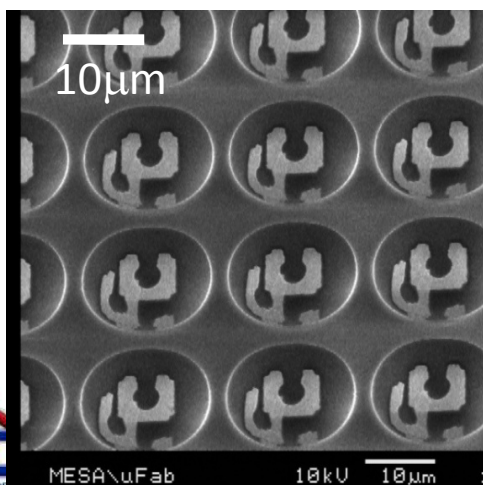


Halos
show
extent
of cavity

E-Beam Lithography



Suspended
Patterned
Membrane



Au-SRRs
After
Liftoff

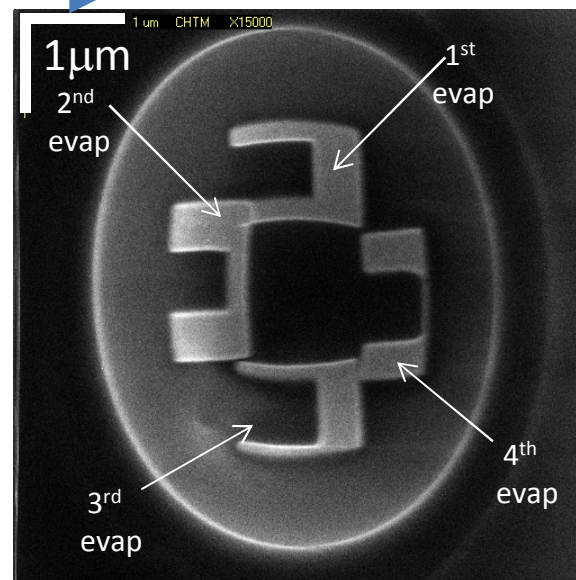
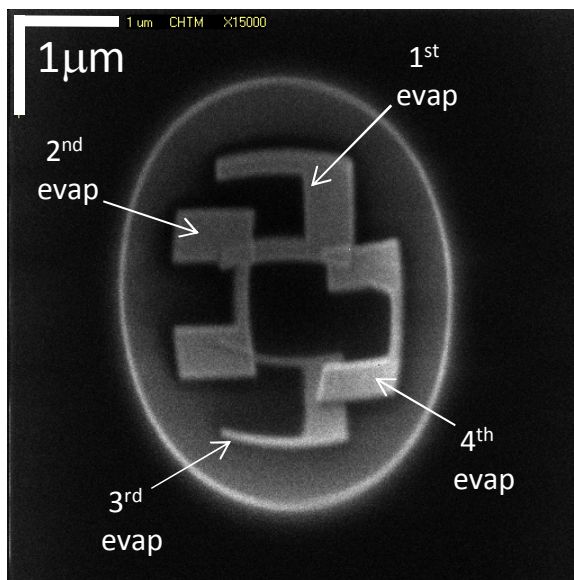
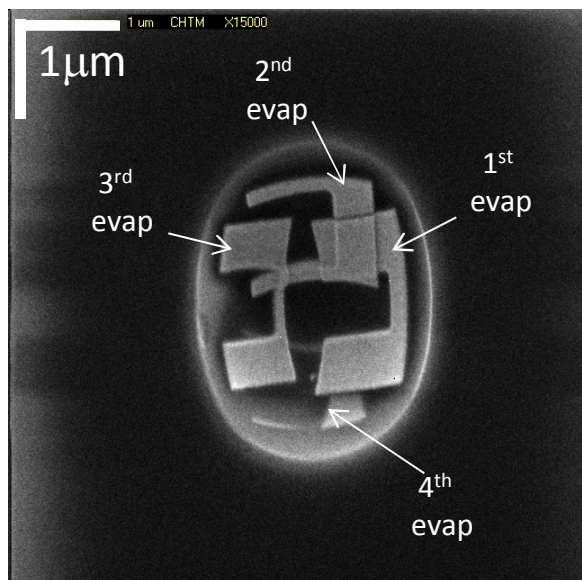




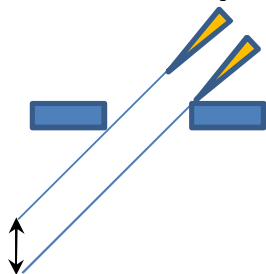
Metamaterials Science & Technology

Curved SRRs via MPL

Increasing Bowl Radius

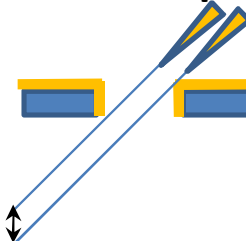


1st Evap



1st Evap linewidth inhomogeneity
due to membrane thickness

4th Evap



4th Evap linewidth inhomogeneity
due to membrane thickness
+ accumulated deposition

240nm total
deposition
through ~340 nm
clear aperture



Metamaterials Science & Technology

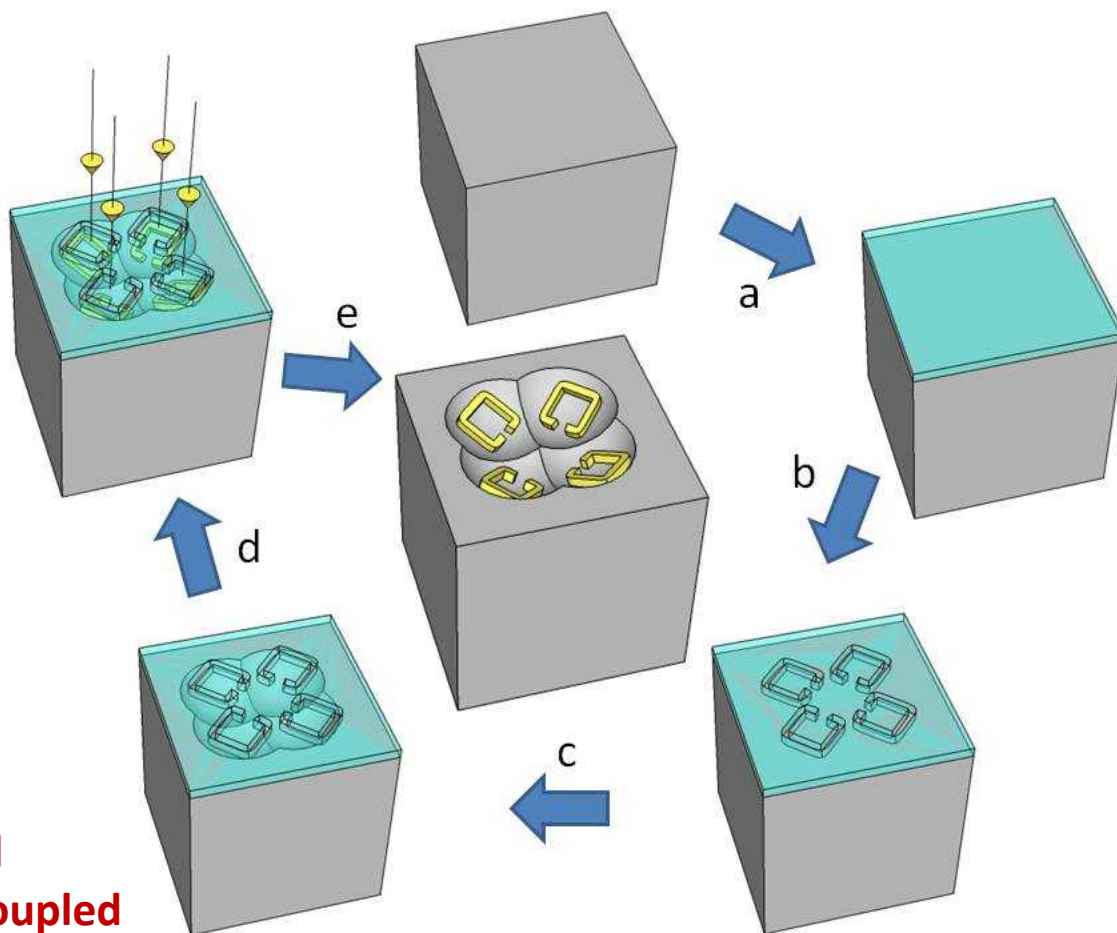
Single-Evaporation MPL

Advantages

- Self-Aligned
- Non-planar resonators
- Planar lithography
- Arbitrary patterns
- Single Evaporation Step
- Scalable
- Layer-by-layer - 3-D

Caveats

- resonator cavity and pattern are tightly coupled

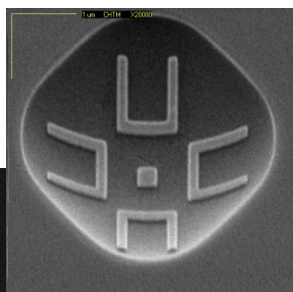
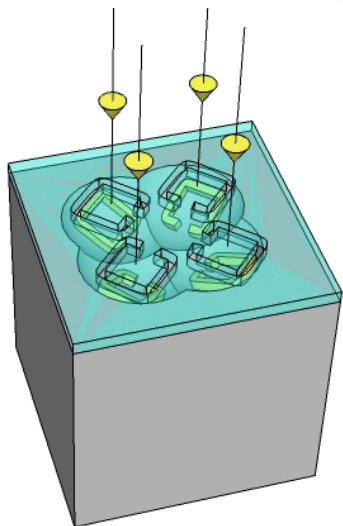




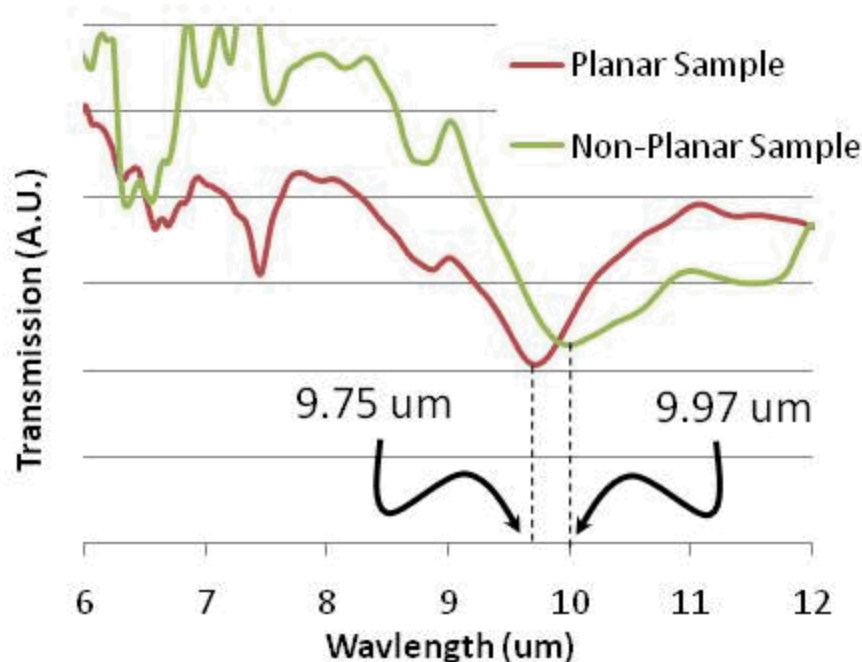
Metamaterials Science & Technology

Fabrication of Out-of-Plane MM Resonators

Single Evaporation
Self-Aligned
Membrane
Projection
Lithography



Un-Normalized Normal Incidence
FTIR Transmission Data



Impact of Out-Of-Plane Resonators

1. Resonance shift due to projection of pattern out of plane
2. Resonance broadening.

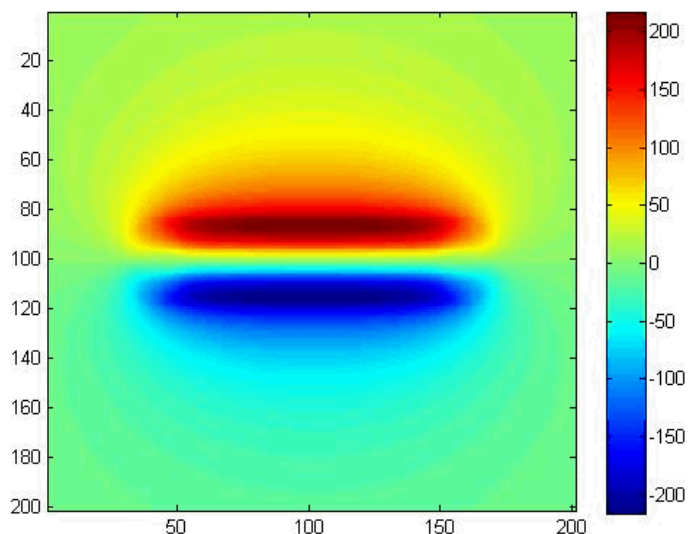
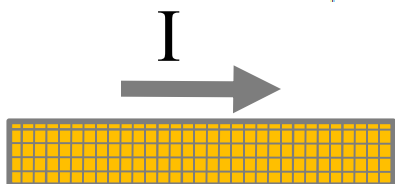


Metamaterials Science & Technology

Calculating Induced Magnetism For A Planar Current Stripe

Magnetic Field

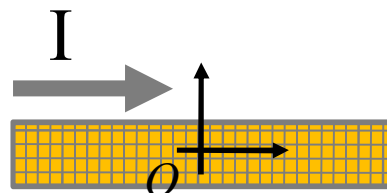
$$B(x, y, z) = \frac{\mu_0 I}{4\pi} \sum \left(\frac{d\vec{l}' \times \vec{R}}{|\vec{R}|^3} \right)$$



Magnetization Vector

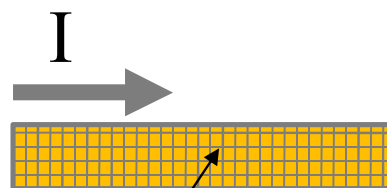
$$\vec{M} \equiv \frac{1}{2c} \sum \vec{r}_i \times \vec{j}_i$$

Origin A:

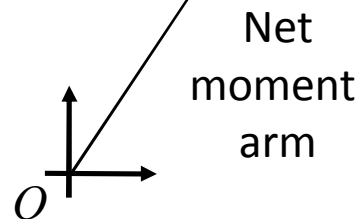


$$\vec{M} = 0$$

Origin B:



$$\vec{M} \neq 0$$



We will always choose the center of mass coordinate as the origin in this work



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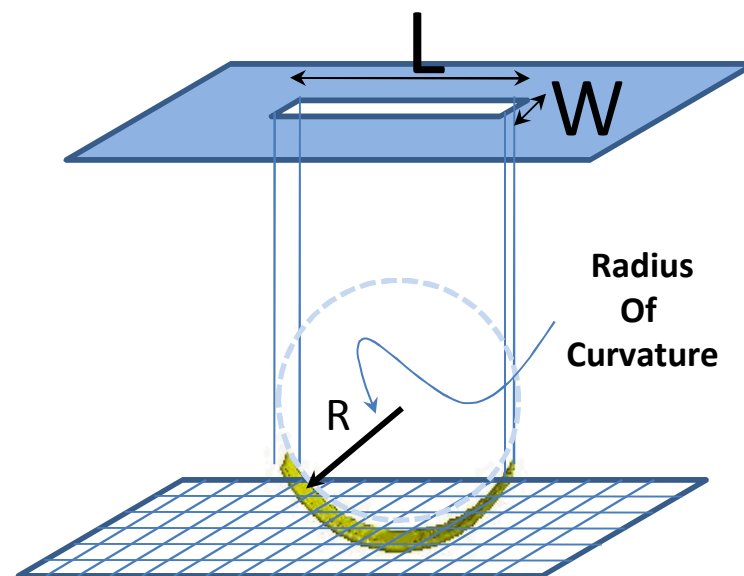
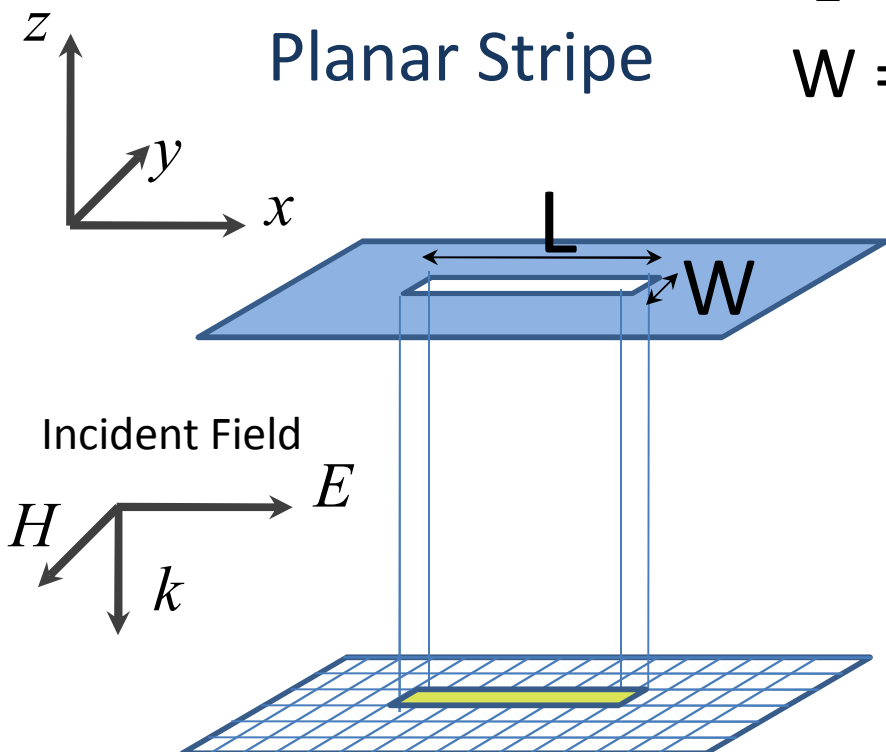
Computation Cell for Single Stripe Geometry

$$L = 1 \mu\text{m}$$

$$W = 0.2 \mu\text{m}$$

Planar Stripe

Curved Stripe



Simplified Current Model:

Assume E-field induces a constant current with only an x-component.

Simplified Current Model:

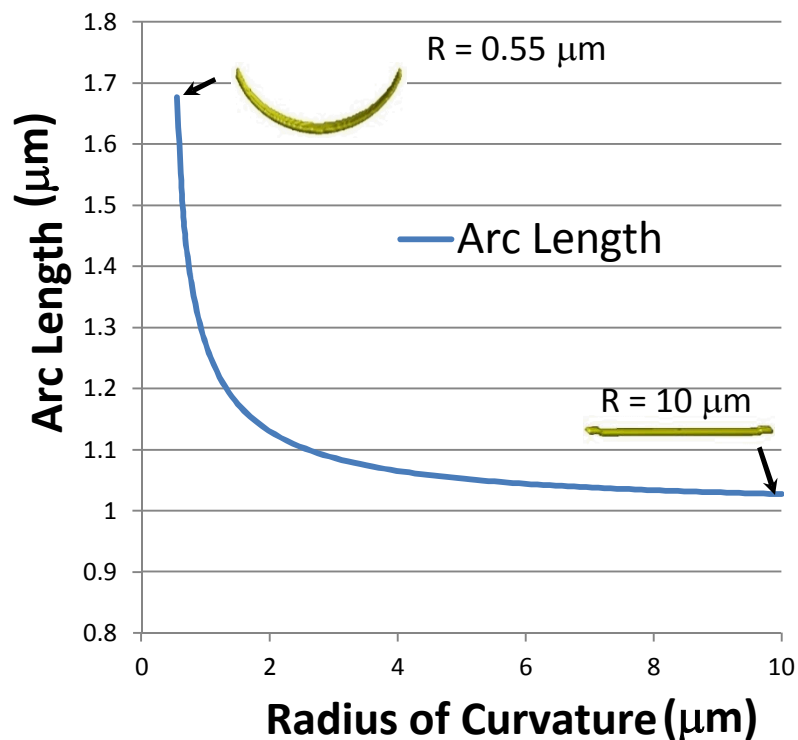
Assume E-field induces a constant current with only an x-component – curvature of metal also creates z-component.



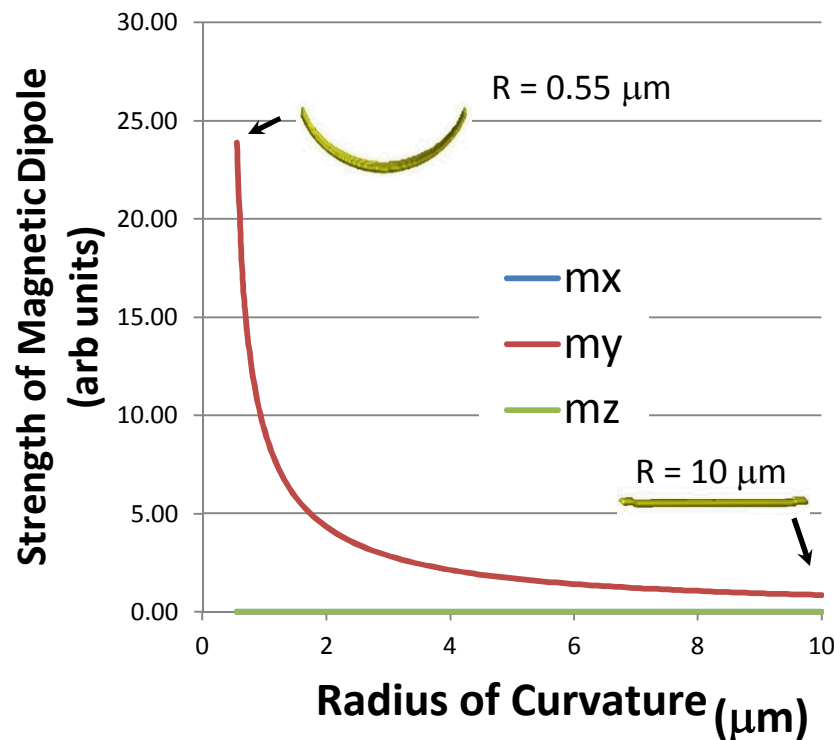
Metamaterials Science & Technology

Effect of Adding Curvature: Single Stripe

Arc Length Dilation



Non-Zero Magnetization

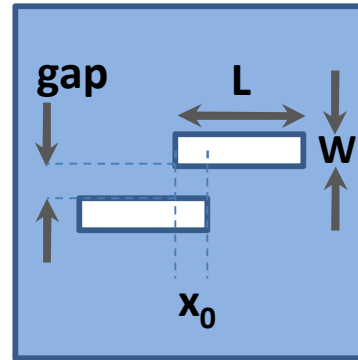
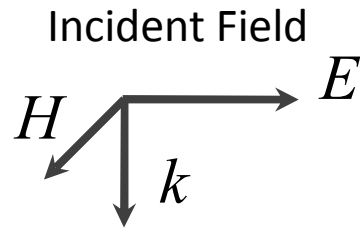


Mask Dimensions:

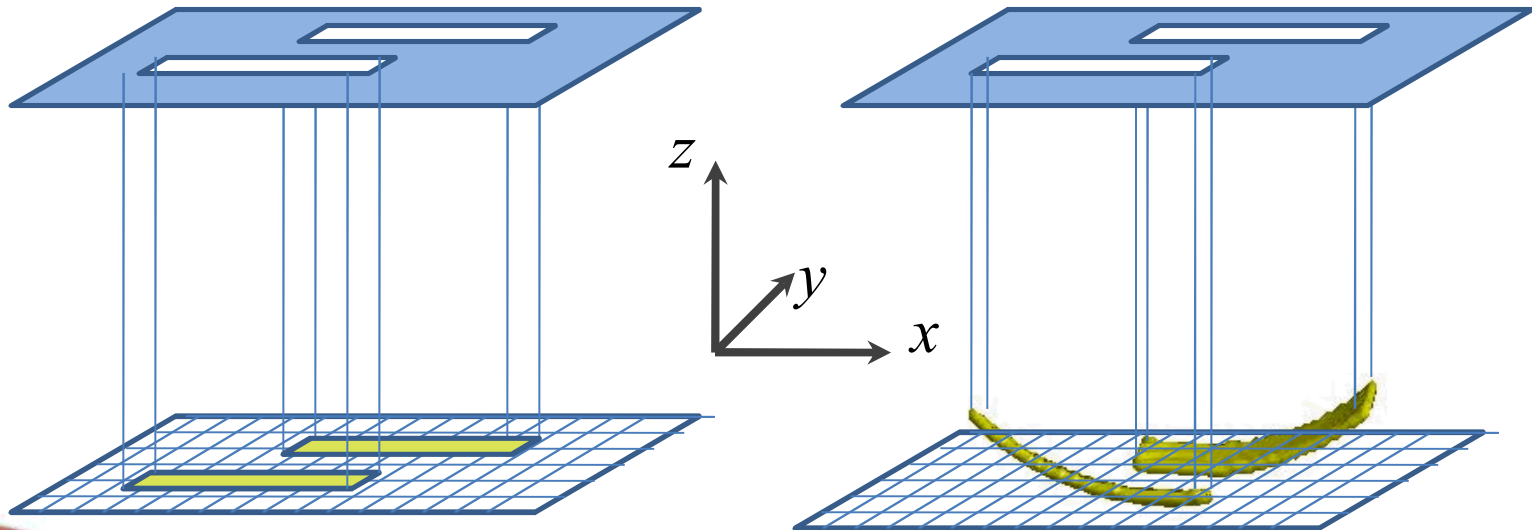
$$\left\{ \begin{array}{l} L = 1 \mu\text{m} \\ W = 0.2 \mu\text{m} \end{array} \right.$$

m_x, m_z are identically 0

Computation Cell for Split Wire Pair Geometry



Top-Down
Schematic of
SWP Membrane

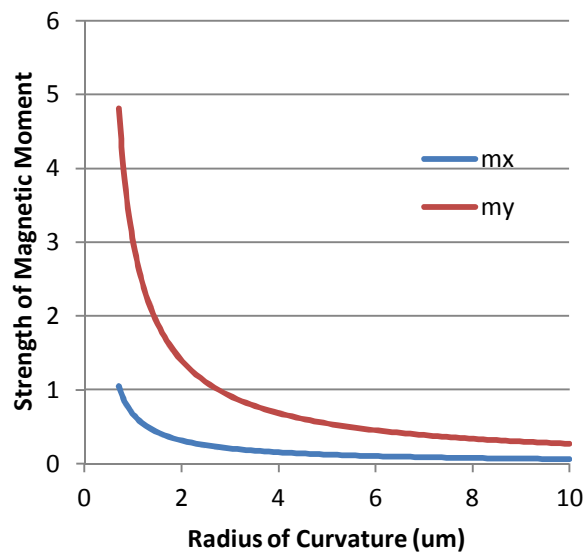




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Effect of Adding Curvature: SWP

Tunable Non-Zero m_x and m_y

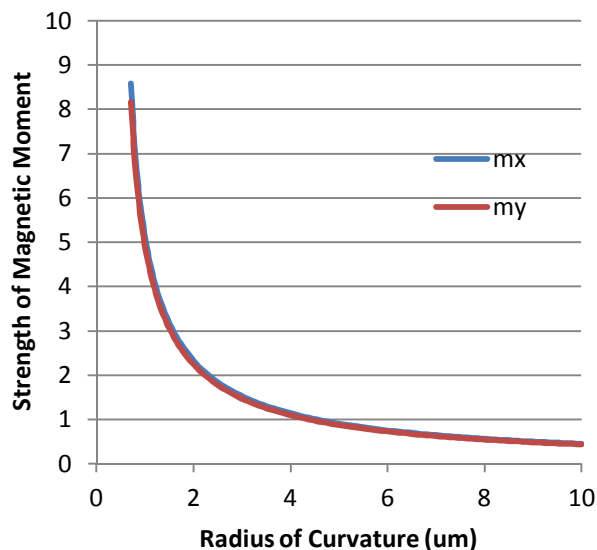


$L = 0.5 \mu\text{m}$

$W = 0.1 \mu\text{m}$

$x_0 = 0.0 \mu\text{m}$

gap = $0.05 \mu\text{m}$

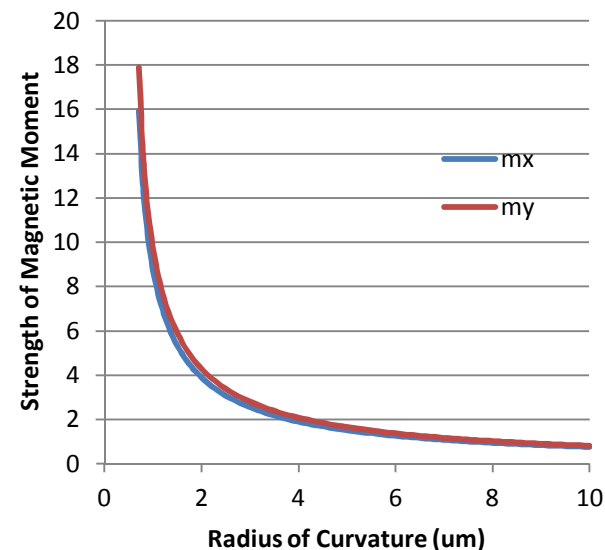


$L = 0.5 \mu\text{m}$

$W = 0.3 \mu\text{m}$

$x_0 = 0.2 \mu\text{m}$

gap = $0.3 \mu\text{m}$



$L = 0.5 \mu\text{m}$

$W = 0.3 \mu\text{m}$

$x_0 = 0.0 \mu\text{m}$

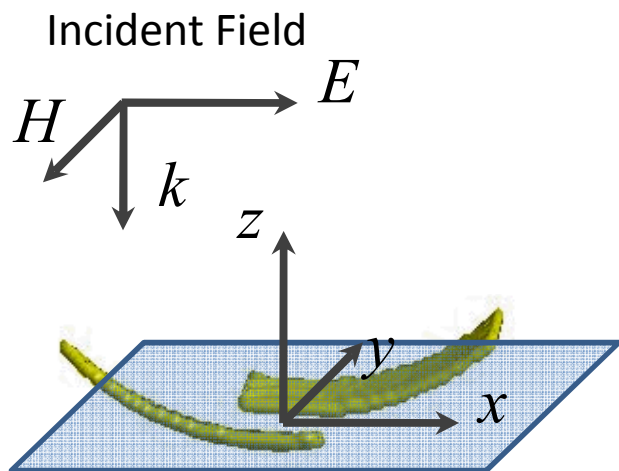
gap = $0.3 \mu\text{m}$



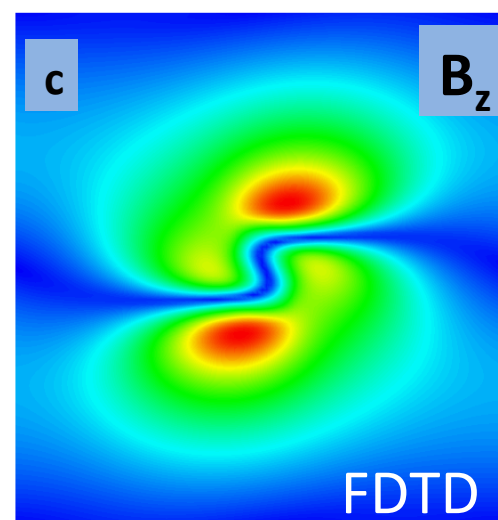
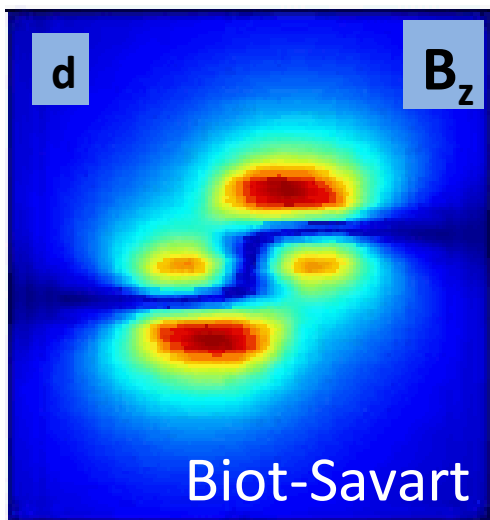
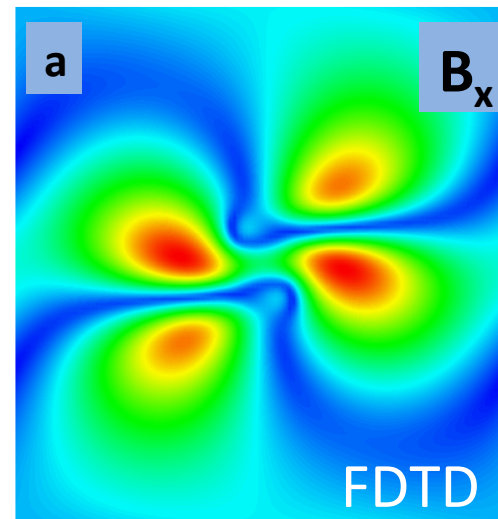
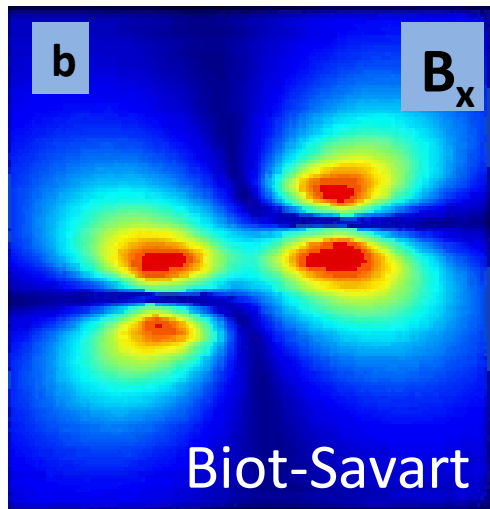
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Simplified Current Model

Biot-Savart vs FDTD



Calculated B-Field
At $z = 0$



Run Time ~ s

Run Time ~ hrs

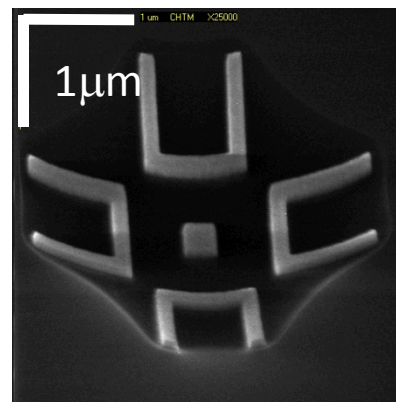
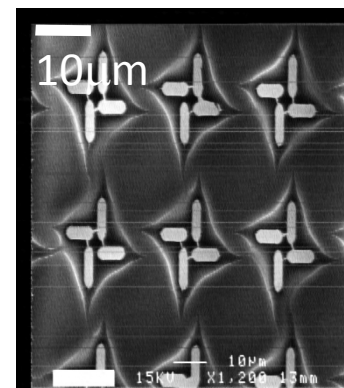
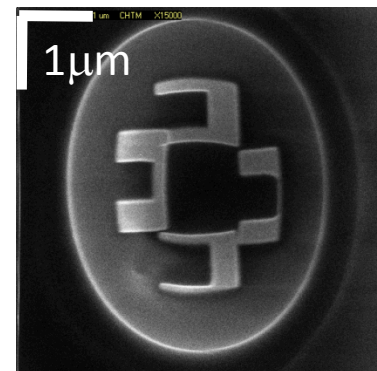
Sandia
National
Laboratories



Metamaterials Science & Technology

Closing Thoughts

1. MPL offers a fabrication route to 3-D IR/Optical Metamaterials.
2. Vision → Hand crafted unit cells with fully 3-D current flow – leveraging symmetry, geometry and material.
3. Expand modeling and simulation capabilities to develop intuition for design space using MPL.





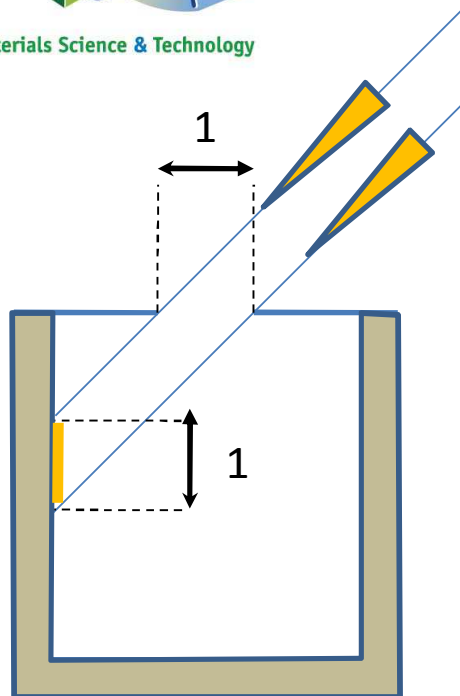
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Backup Slides

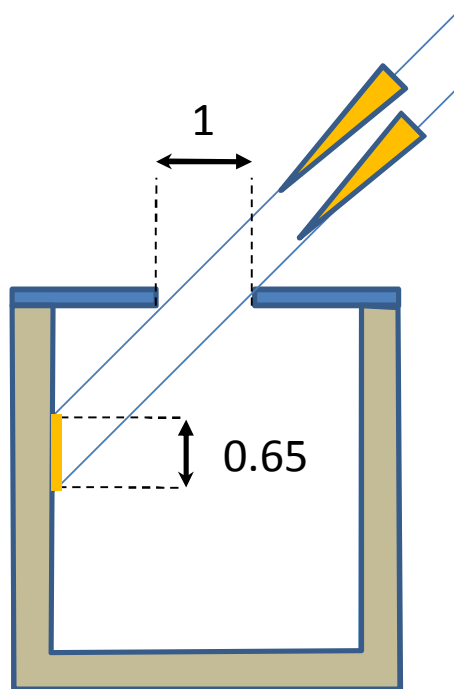


Metamaterials Science & Technology

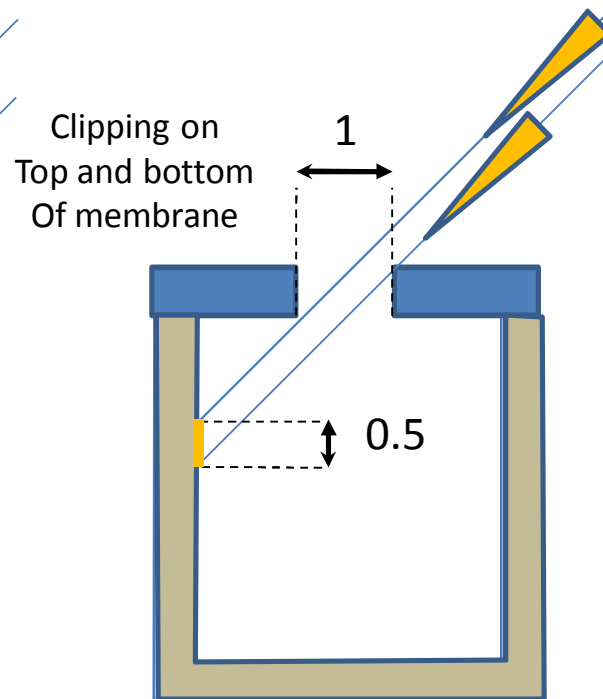
Impact of Membrane Thickness



Ideal
Membrane



Finite
Thin
Membrane



Finite
Thick
Membrane

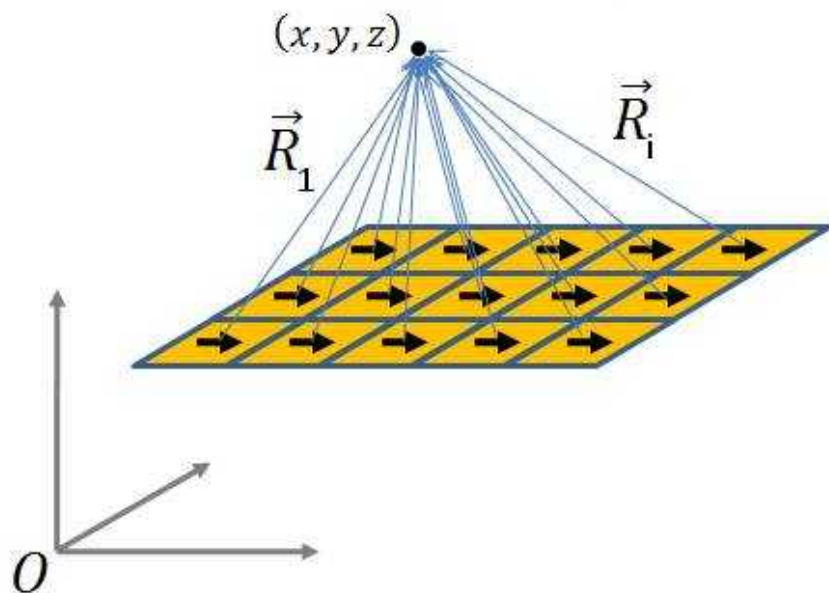
For evaporation at 45° , projected linewidth is decreased by the thickness of the membrane.



Induced Magnetic Response

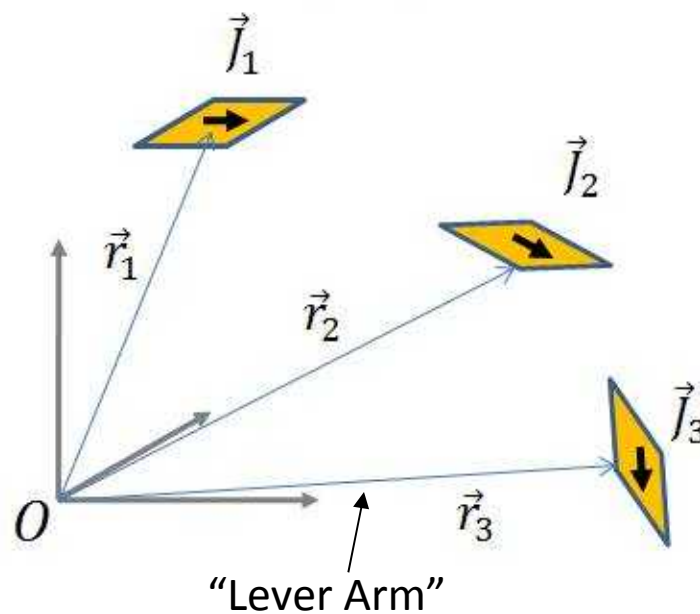
Magnetic Field

$$B(x, y, z) = \frac{\mu_0 I}{4\pi} \sum \left(\frac{dl' \times \vec{R}}{|R|^3} \right)$$



Magnetization Vector

$$\vec{M} \equiv \frac{1}{2c} \sum \vec{r}_i \times \vec{J}_i$$





Metamaterials Science & Technology

Magnetization Vector

$$\vec{M} \equiv \frac{1}{2c} (\vec{r} \times \vec{J})$$

Bulk Material Property

$$\vec{H} = \frac{1}{\mu} \vec{B}$$

$$\vec{H} = \vec{B} - 4\pi \vec{M}$$

Nano Antenna Property

$$A(\vec{r}) = \text{Dipole Term} + C \int J(\vec{r}') (\vec{n} \cdot \vec{r}') dV'$$

Electric
Quadrupole
Term

Magnetic
Dipole
Term

$$\frac{1}{2c} [(\vec{n} \cdot \vec{r}') \vec{J} + (\vec{n} \cdot \vec{J}) \vec{r}'] + \underbrace{\frac{1}{2c} (\vec{r}' \times \vec{J}) \times \vec{n}}_{\vec{M}}$$

Both the material parameter μ and the far-field scattering behavior depend on the magnetization vector of the meta – “atoms”.

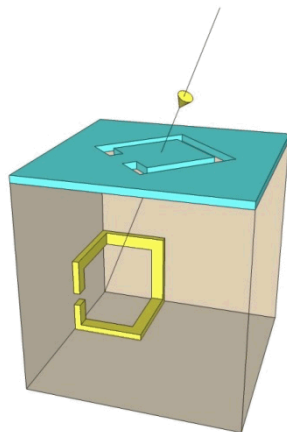
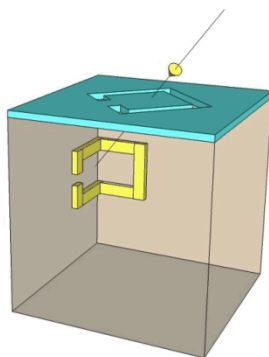
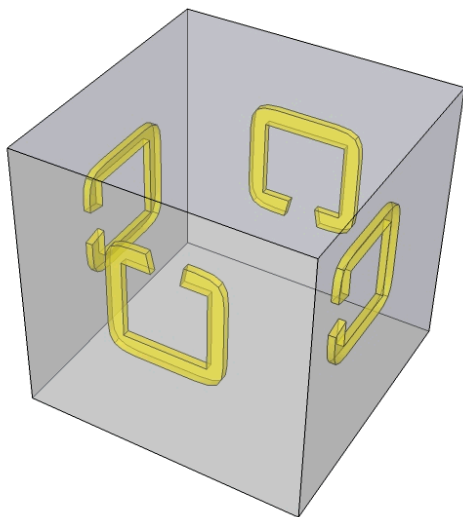


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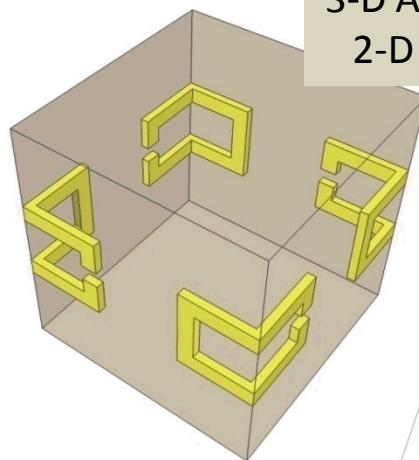
MPL Enables Truly 3-D Resonators

3-D Could Be or 2.5-D

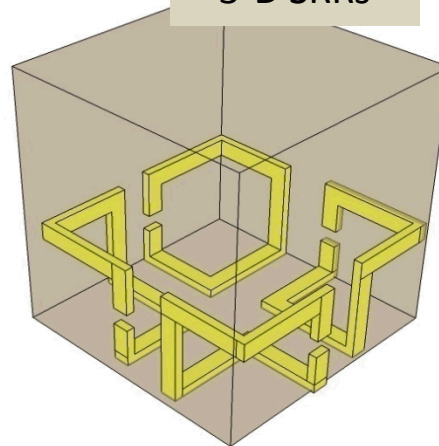
3-D Array of Planar SRRs



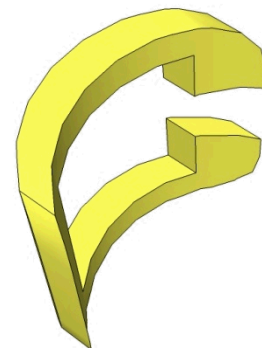
3-D Array of 2-D SRRs



3-D Array of 3-D SRRs



Cylindrical



Spherical

